

Additional Program (Late News Paper Program)

Oral Session

31B-2: Nanostructure Engineered Devices
31B-2-5L 14:50 Direct Fabrication of WxCy SNS Josephson Junction by Using Focused-ion-beam Chemical Vapor Deposition J. Dai 1,2, K. Onomitsu 2, R. Komatani 1, Y. Krockenberger 2, H. Yamaguchi 2, S. Ishihara 1 and S. Warisawa 1, 1 Univ. of Tokyo and 2

Poster Session

1P-7: 15:40-17:40 Poster Session I
Lithography and Metrology
1P-7-106L Electron Beam Current Dependence of Surface Potential Distribution at a Resist Film A. Osada, M. Otani, K. Kumagai and M. Kotera, Osaka Inst. of Technol., Japan

2P-11: 14:40-16:40 Poster Session II

Nanocarbons		Nanofabrication		
2P-11-114L Plasma-oxidized Al ₂ O ₃ for Gate Dielectrics in Graphene Field Effect Transistors G.-H. Park, M.-H. Jung, S. Inomata, H. Fukidome, T. Suemitsu, T. Otsuji and M. Suemitsu, Tohoku Univ., Japan	2P-11-115L Position-controlled Direct Graphene Synthesis on SiO ₂ Surface by Laser Irradiation K. Koshida, K. Gumi, Y. Ohno, K. Maehashi, K. Inoue and K. Matsumoto, Osaka Univ., Japan	2P-11-116L Highly Sensitive Biosensors Based on Fragment-modified Graphene FET S. Okamoto, T. Ikuta, S. Zaifuddin, Y. Ohno, K. Maehashi, K. Inoue and K. Matsumoto, Osaka Univ., Japan	2P-11-117L Role of Au Nanoparticle Decoration on Cross-linked WO ₃ Nanodomains for Selective Gas Sensing Y.-S. Shim 1,2, H.G. Moon 1, D.H. Kim 1, H.W. Jang 3, Y.S. Yoon 2, KIST, 2 Yonsei Univ. and 3 Seoul Natl. Univ., Korea	2P-11-118L Direct EB Patterning of Functional Oxide Mask on Non-plant Surfaces Applied for GaAs Nanostructures Y. Matsuoka, K. Ashida and T. Kaneko, Kwansai Gakuin Univ., Japan

Nanomaterials		BioMEMS, Lab on a Chip		
2P-11-119L Hydrothermal Synthesis and Electrochemical Characterization of TiO ₂ (B) Nanosheets for Battery H.Y. Wu 1, M.H. Hon 1, C.Y. Kuan 1 and I.C. Leu 2, 1 National Cheng Kung Univ. and 2 Natl. Univ. of Tainan, Taiwan	2P-11-120L Photophysical Properties of Europium doped Ceramics Nanoparticles in Bio/medical Polymer Matrix S. Abe 1, Y. Hamba 1, S. Yamagata 1, M. Uo 2, J. Iida 1, T. Kiba 1, A. Murayama 1 and F. Watari 1, 1 Hokkaido Univ. and 2 Tokyo Medical and Dental Univ., Japan	2P-11-121L Sensor Application Based on CVD-synthesized Graphene S. Zaifuddin 1, S. Okamoto 1, Y. Ohno 1, T. Ikuta 1, K. Maehashi 1, M. Miyake 1,2 and K. Matsumoto 1, 1 Osaka Univ. and 2 AIXTRON, Japan	2P-11-122L A Microstructure-embedded Microfluidic Chip for Continuous Sample Separating Applications S.K. Hsiung 1, R.C. Lin 1, H.C. Lee 2, Y.F. Chen 3, C.T. Wu 3 and C.H. Lin 2, 1 Fooyin Univ., 2 Natl. SunYat-Sen Univ. and 3 Gene Target Technol., Taiwan	2P-11-123L Fabrication of Hydrophilic Polydimethylsiloxane (PDMS) with Wrinkled Surface D.K. Lee, C.K. Oh, and O.C. Jeong, Inje Univ, Korea

Microsystem Technology and MEMS				
2P-11-124L Supporting Structure Optimization for a High-Frequency Quartz Resonator J. Ji, H. Ohigawa, M. Zhao and H. Yu, T. Ueda, Waseda Univ., Japan	2P-11-125L Dry Etching of Quartz Glass using C ₄ F ₈ /He Plasmas for Microtrenches with Photoresist and Metal Mask Y.-H. Tang, M.-J. Huang and M.-H. Shiao, Natl. Applied Res. Labs., Taiwan	2P-11-126L Design and Fabrication of Tip attached MEMS Test Socket J.M. Lee 1, S.W. Kim 1, J.W. Nam 2, B.H. Kim 3, C.S. Cho 4 and H.S. Choi 1, 1 DGIST, Korea, 2 CoreMEMS, USA, 3 Catholic Univ. of Daegu and 4 Kyungpook Natl. Univ., Korea	2P-11-127L Fabrication of High Resolution Tactile Sensor Using Through-Si-via Technology H. Yokoyama 1, M. Sohagawa 1, T. Kanashima 1, M. Okuyama 1 and H. Noma 2, 1 Osaka Univ. and 2 Advanced Telecommunications Res. Inst. Internatl., Japan	2P-11-128L High-responsivity Wavelength-selective Gate/body-tied MOSFET-type Photodetector with Metal-grating S.-H. Jo 1, H.H. Lee 1, M. Bae 1, J. Choi 1, J. Ahn 1, S. Kim 1, H.-K. Lyu 2 and J.-K. Shin 1, 1 Kyungpook Natl. Univ. and 2 Daegu-Gyeongbuk Inst. of Sci. and Technol., Korea Kyungpook Natl. Univ. and 2 Daegu-Gyeongbuk Inst. of Sci. and

Withdrawn List

Lithography and Metrology 1P-7-2 Withdrawn	Lithography and Metrology 1P-7-8 Withdrawn
Generation and Transport of Volatile Metal Hydrides in EUVL upon Atomic Hydrogen D. Ugur 1,2, A.J. Storm 1, R. Verberk 1, J.C. Brouwer 2 and W.G. Sloof 2, 1 TNO Sci. & Industry and 2 Delft University of Technol., The Netherlands	Phase Defect Printability Prediction using EUV Microscope Technique T. Terasawa 1, T. Amano 1, O. Suga 1, Y. Arisawa 1, T. Yamane 1, H. Watanabe 1 and M. Toyoda 2, 1 EIDEC and 2 Tohoku Univ., Japan

2C-8: Nanomaterials III 2C-8-1 Withdrawn	2C-9: Nanomaterials IV 2C-9-4 Withdrawn
9:00 Efficiency Control of Fluorescence Resonance Energy Transfer FRET from Protein Donors to semiconductor QDs M. Ghali, Kafrelsheikh Univ., Egypt	11:35 Manipulation of the Optical Spin Injection in a Precisely Chosen Composition of Magnetic/non-magnetic Hybrid Structure M. Ghali, Kafrelsheikh Univ., Egypt

Nanodevices 2P-11-24 Withdrawn	Nanodevices 2P-11-29 Withdrawn	BioMEMS, Lab on a Chip 2P-11-122L Withdrawn	Microsystem Technology and MEMS 2P-11-109 Withdrawn
Cd-free Color Tunable I-III-VI Semiconductor NCs for Color Converter in white Led W. Chung, H.C. Jung, C.H. Lee and S.H. Kim, Korea Univ., Korea	High Selective Etching of Si/Si ₃ N ₄ in Inductively Coupled Plasma A. Rubin, King Abdullah Univ. of Sci. and Technol., Saudi Arabia	A Microstructure-embedded Microfluidic Chip for Continuous Sample Separating Applications S.K. Hsiung 1, R.C. Lin 1, H.C. Lee 2, Y.F. Chen 3, C.T. Wu 3 and C.H. Lin 2, 1 Fooyin Univ., 2 Natl. SunYat-Sen Univ. and 3 Gene Target Technol., Taiwan	A High-efficiency Beam Splitter of a Double-groove Blazed Grating using Ultra-precision Manufacturing J.-H. Hsu 1, C.-H. Lee 2 and R. Chen 1, 1 Natl. Tsing Hua Univ. and 2 Feng Chia Univ., Taiwan